

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings of claims in the application:

LISTING OF CLAIMS:

1. (previously presented) A method of depositing an amorphous layer containing fluorine and carbon on a substrate in a vacuum, comprising:

depositing said amorphous layer via an ion gun adapted to eject ions in a form of a beam of accelerated ions created from at least one compound containing fluorine and carbon in gas or saturated vapor form fed to the ion gun,

wherein the substrate is an ophthalmic lens, and the amorphous layer containing fluorine and carbon is an exterior layer of an antireflection stack of the ophthalmic lens.

2. (canceled)

3. (previously presented) The method according to claim 1, wherein the ion gun is fed with the at least one compound containing fluorine and carbon mixed with oxygen or at least one rare gas.

4. (previously presented) The method according to claim 1, wherein the compound containing fluorine and carbon comprises at least one aliphatic or cyclic fluorocarbon

compound, at least one aliphatic or cyclic fluorinated hydrocarbon, or a mixture thereof.

5. (previously presented) The method according to claim 1, wherein the compound containing fluorine and carbon comprises perfluorocyclobutane (C_4F_8) or a mixture with at least one other fluorocarbon compound comprising tetrafluoromethane (CF_4) or hexafluoromethane (C_2F_6).

6. (currently amended) The method according to claim 1, wherein the ~~ophthalmic lens is a plastics material~~ ophthalmic lens substrate comprises a plastics layer.

7. (currently amended) The method according to claim 1, further comprising fabricating the antireflection stack by the following steps:

- physical vapor-phase deposition (PVD) in a vacuum of three layers respectively having, from an interior toward the exterior layer, a layer having a first refractive index/a layer having a second refractive index/a layer having the first refractive index, ~~type~~ or a stack of $\text{ZrO}_2/\text{SiO}_2/\text{ZrO}_2$; and

- depositing the exterior layer containing mostly fluorine and carbon using the ion gun,

wherein the second refractive index is lower than the first refractive index.

8. (previously presented) The method according to claim 7, wherein the PVD includes evaporation by electron bombardment of the material to be deposited.

9. (currently amended) The method according to claim 7, wherein each said ~~depositing~~ PVD step is carried out at a pressure less than or equal to 10^{-2} Pa.

10-17. (cancelled)

18. (currently amended) The method according to claim 8, wherein each said ~~depositing~~ PVD step is carried out at a pressure less than or equal to 10^{-2} Pa.

19. (previously presented) The method according to claim 3, further comprising fabricating the antireflection stack by the following steps:

- physical vapor-phase deposition (PVD) in a vacuum of three layers respectively having, from an interior toward the exterior layer, a high refractive index/a low refractive index/a high refractive index, or $\text{ZrO}_2/\text{SiO}_2/\text{ZrO}_2$;

- depositing the amorphous external layer containing mostly fluorine and carbon using the ion gun.

20. (cancelled)

21. (previously presented) The method according to claim 1, wherein a refractive index characteristic of the exterior layer is 1.35-1.39.

22. (new) The method according to claim 6, wherein the plastics layer comprises a resin.

23. (new) The method according to claim 22, wherein the resin is covered with anti-abrasion varnish.

24. (new) The method according to claim 1, wherein the amorphous layer has antisoiling property.

25. (new) The method according to claim 1, wherein the antireflection stack does not include a final antisoiling layer.